



UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE
 United States Patent and Trademark Office
 Address: COMMISSIONER FOR PATENTS
 P.O. Box 1450
 Alexandria, Virginia 22313-1450
 www.uspto.gov



Bib Data Sheet

CONFIRMATION NO. 8462

SERIAL NUMBER 10/615,881	FILING DATE 07/10/2003 RULE	CLASS 438	GROUP ART UNIT 2813	ATTORNEY DOCKET NO. 9862- 000015/US/CPA
-----------------------------	---------------------------------------	--------------	------------------------	--

APPLICANTS

Jae-Hyun Yeo, Incheon-city, KOREA, REPUBLIC OF;

Young-Sun Kim, Suwon-si, KOREA, REPUBLIC OF;

Sung-Tae Kim, Seoul-city, KOREA, REPUBLIC OF; In-Sung Park, Seoul-city, KOREA, REPUBLIC OF;
Gi-Vin Im, Suwon-city, KOREA, REPUBLIC OF;

** CONTINUING DATA *****

This application is a CIP of 10/047,706 01/15/2002 PAT 6,734,480

** FOREIGN APPLICATIONS *****

REPUBLIC OF KOREA 2002-42217 07/18/2002
REPUBLIC OF KOREA 2001-3165 01/19/2001

IF REQUIRED, FOREIGN FILING LICENSE GRANTED

** 10/07/2003

Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY KOREA, REPUBLIC OF	SHEETS DRAWING 15	TOTAL CLAIMS 29	INDEPENDENT CLAIMS 3
35 USC 119 (a-d) conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after Allowance				
Verified and Acknowledged	Examiner's Signature <i>TN</i>	Initials		

ADDRESS

30593
HARNESS, DICKEY & PIERCE, P.L.C.
P.O. BOX 8910
RESTON, VA
20195

TITLE

Method of forming material using atomic layer deposition and method of forming capacitor of semiconductor device using the same

☐ All Fees